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Substitute for form 1449/PTO		<i>Complete If Known</i>	
		Application Number	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>		Filing Date	
		First Named Inventor	David J. Christie
		Art Unit	
		Examiner Name	
Sheet <b>2</b>	of <b>3</b>	Attorney Docket Number	AE2002-006CIP

<b>NON PATENT LITERATURE DOCUMENTS</b>				
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		T <sup>2</sup>
<i>dm</i>	1	JUNQING LU et al; Sep/Oct 2001, pp.. 2652-2663		
		Trench filling by ionized metal physical vapor deposition;		
	2	VLADIMIR KOUZNETSOV et al., Surface and Coatings Technology 122 (1999); pp. 290-293		
		A Novel Pulsed Magnetron Sputter Technique Utilizing Very High Target Power Densities		
	3	KAROL MACAK et al., Jul/Aug 2000; pp. 1533 - 1537		
		Ionized Sputter Deposition Using an Extremely High Plasma Density Pulsed Magnetron Discharge		
	4	J.T. GUDMUNDSSON et al., May 28, 2001, Volume 78, Number 22; pp. 3427-3429		
		Evolution of the Electron Energy Distribution and Plasma Parameters in a Pulsed Magnetron Discharge		
	5	A.P. EHIASARIAN et al., Vacuum 65 (2002); pp. 147-154		
<i>dm</i>		Influence of High Power Densities on the Composition of Pulsed Magnetron Plasmas		

Examiner Signature	<i>Adrienne M. Christie</i>	Date Considered	6/1/05
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	6	OTHON R. MONTEIRO, May/Jun 1999; pp. 1094-1097		
		Novel Metallization Technique for Filling 100-nm-wide Trenches and Vias with Very High Aspect Ratio		

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